Quarterly Progress Report
7 January through 6 April 1963
Contract No. DA36-039-AMC-00118(E)
Order No. 5389-PM-63-91
PR\&C No. 63-ELN/R-6505

Fort Monmouth, New Jersey
Fignal Research and Development Laboratory
Formy


Qualified requestors may obtain copies of this report from ASTIA. ASTIA release to OTS not authorized.

# USE OF OPTICAL MASERS IN DISPLAYS AND PRINTERS 

Technical Requirement SC L-4396, 6 June 1962 Contract No. DA-36-039-AMC-00118(E) Order No. 5389-PM-63-91; PR \&C No. 63-ELN/R-6505<br>to<br>U. S. Army Signal Research and Development Laboratory Fort Monmouth, New Jersey

The objective of this study and investigation is a significant improvement in the state of the art among electro-optical input/output devices using the Laser as an electro-optic tool.

Report prepared by Dr. H. Fleisher and Dr. W. Kulcke
Development Laboratory, Data Systems Division
Purpose ..... 1
Abstract ..... 2
Next quarter Plans ..... 3
Discussion ..... 4
Introduction ..... 4
Digital Light Deflector ..... 5
General ..... 5
Accomplishments ..... 7
Calculation of Maximum Splitting Angle ..... 12
Calculation of the Relation between the Number of Positions ..... 13
and the Aperture, and the Minimum Spot Size
Conical Refraction ..... 15
General ..... 15
Accomplishments ..... 17
Electrically Controlled Fresnel Zone Lens ..... 18
Conclusions ..... 24
Publications, Lectures, Reports, and Conferences ..... 25
Key Personnel ..... 26
Appendix I. Calculation of Improved Electro-Optic Light ..... 34
Deflector Using Conical Refraction
Appendix II. Calculation of the Cone Angle $\xi$ of Conical Refraction ..... 36
FIGURES

1. Digital light deflector for collimated beams. ..... 5
2. Digital light deflector for convergent beams. ..... 7
3. Half-wave length voltages $\mathrm{V}_{\lambda} /{\underset{\sim}{2}}^{\text {of }} \mathrm{NH}_{4} \mathrm{H}_{2} \mathrm{PO}_{4}, \mathrm{KH}_{2} \mathrm{PO}_{4}$, ..... 8 and $\mathrm{KD}_{2} \mathrm{PO}_{4}$ as a function of wave length.
4. Orientation of calcite crystal for maximum splitting of ..... 9 ordinary and extraordinary rays.
5. Minimum aperture, $a$, of the convergent beam deflector for ..... 10N resolvable spots.
6. Minimum spot size of a convergent beam deflector of $a=1.2$ ..... 11 cm aperture.
7. Compensation of angular birefringence. ..... 11
8. Calculation of maximum splitting angle between ordinary and ..... 12extraordinary rays.
9. Diffraction problem in the digital def.ector. ..... 14
10. Light deflection by conical refraction ..... 16
11. Improved light deflection by conical refraction. ..... 16
12. Electrically controlled Fresnel zone lens. ..... 19
13. Calculation of improved electro-optic light deflector. ..... 35
14. Calculation of cone angle g . ..... 36

## PURPOSE

Speed and storage capabilities of data processing system have increased steadily in the past decade. The display of results and information produced by computers handling problems of such high speeds must be accomplished by similarly sophisticated approaches.

In addition to the dieplay and hard copy production of alpha-numeric material, we must consider two-dimensional and multidimensional display of graphic and analog type information. The display must be compatible with the human in terms of matching his frequency range of sensitivity, resolving power, and image retention.

The immediate purpose of this study is to develop laser technology for computer input-output devices, and to prepare a laboratory-type demonstration to indicate the ability to modulate electronically and deflect a light beam. This task is preparatory to further development of a complete laser display system.


#### Abstract

We investigated the deflection of laser beams using digital light deflectore and conical refraction, and the focusing of laser beams with a Fresnel sone lens. The results indicate that laser beams can be accurately deflected by means of a digital light deflector.

Conical refraction shows promise for analog deflection of the bearr and the Fresnel zone plate lens when constructed with proper electrodes is aitable for focus/defocus control.

The conclusion indicates that digital electro-optic deflection of intense light beams is feasible and could lead to the realization of practical laser. display and printing apparatus.


## NEXT QUARTER PLANS

## DIGITAL LIGHT DEFLECTOR

We will receive and assemble the parts for the 8 position, one-dimensional light deflector. Using this model, we will work with collimated light beams and use semitransparent electrodes on the electro-optic crystals. Since semitransparent electrodes give rise to considerable light absorption if the deflector comprises many stages, we will investigate other possible electrodes. These include slit electrodes, gratings, or meshes, as well as improved semitransparent electrodes. The use of convergent light beams requires further investigations of compensation of zero field birefringence of off-axis rays.

CONICAL REFRACTION
We plan to obtain crystals of sufficient optical quality, cut perpendicular to their optical axis, and large enough to show an output circle for quantitative investigations. These crystals could be naphthalene or anthracene or an inorganic mineral such as aragonite. We plan to measure quantitatively the intensity distribution around the output circle for different polarization directions of the incoming light to help resolve discrepancies. FRESNEL LENS

We will continue in our endeavors to obtain the Fresnel zone plate electrodes configuration of the proper resolution.

## DISCUSSION

## INTRODUCTION

Light propagates through an isotropic medium in a straight line, independent of polarization. The direction of the light is changed only by changing the medium or by introducing anisotropy.

In the past, control of light deflection was mainly performed by mechanically changing the boundary conditions, e.g., changing the angle of incidence at the surface of a mirror. The mechanical inertia involved in this process of deflection limits the deflection speed to frequency responses in the range of some $10,000 \mathrm{cps}$.

The electrically controlled light deflectors described in this report are based on the principle of generation of anisotropy in the medium. The generated anisotropy is without inertia up to microwave frequencies. Three foncepts are described in this report. One of them is of a digital nature, where a light beam can be switched discontinuously to a sequence of discrete positions by applying one fixed electrical voltage to properly selected electrooptic switches. Another concept is of analog nature, where a light beam can be directed to a continuous sequence of positions by changing the voltage applied to one electro-optic active crystal. This deflector is based on the phenomenon of internal conical refraction. The third concept refers to a Fresnel lens structure which allows focusing/defocusing action under the influence of an electric field. Depending on the application, it could be operated under digital or analog conditions.

## DIGITAL LIGHT DEFLECTOR

## General

Unpolarized light, passing through a birefringent crystal such as calcite, aplits into an ordinary and an extraordinary ray which propagate through the suitably oriented crystal in different directions. In the digital light deflector, linearily polarized light can be controlled by electro-optic switches to pass through calcite crystals as either the ordinary or the extraordinary ray. The principle is shown in Figure 1, where a linearily polarized collimated light beam of small diameter passes through an arrangement of


Figure 1. Digital light deflector for collimated beams.
electro-optic awitches A and calcite crystals B. The original polarization direction is assumed to be vertical. The electro-optic switches, $A$, change the direction of polarization from vertical to horizontal or vice versa after application of the half-wave length voltage $V_{\lambda / 2}$. For the witch positions
shown in Figure 1, no voltage is applied to $A_{1}$, and the polarization direction of the incident light beam remains vertical traversing this switch. The light passes through the first calcite crystals, $B_{1}$, as the ordinary ray. Since $V_{\lambda / 2}$ is applied to the second switch, $A_{2}$, the light leaves this switch horizontally polarized and passes through calcite crystal $B_{2}$ as the extraordinary ray. No voltage is applied to $A_{3}$, and therefore, the polarization direction of the beam remains horizontal, the beam also traversing calcite crystal $B_{3}$ as the extraordinary ray.

In this way, with several switches and calcite crystals arranged as shown in Figure 1, a multiplicity of different output loci can be switched digitally. The thickness of the calcite crystals can be changed from stage to stage in a binary sequence. In this case, a maximum of different output loci can be switched by a minimum of switches.

We are considering two versions of the digital light deflector - collimated beam and converging beam. The deflector (Figure l) for a collimated beam is the simpler of the two, but it has some limitations with regard to intensity and resolution of the deflected beam. In our effort to achieve higher resolution and higher intensity, we are also studying a second version of the digital light deflector (Figure 2) which involves sending a converging beam through the device and focusing on the other side. In this way, we can make full use of the aperture, $a$, of the device and obtain maller useable spots of light, thus increasing the number of deflection positions for a given crystal size. For demonstration, referring to Figure 2, another


Figure 2. Digital light deflector for convergent beams. (For symmetrical deflection, calcite crystal $\mathrm{B}_{3}$ is arranged upside down.)
selection of electro-optic switches is chosen by which the beam is deviated in the calcite crystals $B_{1}$ and $B_{3}{ }^{\circ}$

In view of the design problems associated with the converging beam deflector, we have decided to work initially on a model of the deflector utilizing the narrow collimated beam. We note that this device possesses potential for displays, production of hard copy, and interrogation of optical read-only memories.

## Accomplishments

During this reporting period we:
(1) started the design of a bread-board model of a linear digital light deflector for 8 positions, utilizing a collimated beam of about 1 mm diam. This model is equipped with calcite crystals of 5 by 12 mm aperture and it
will be about 20 cm long. The bread-board model will be delivered to USASRDL after completion.
(2) measured the half-wave length voltages $V_{\lambda / 2}$ of the electro-optic active materials ammonium dihydrogen phosphate $\mathrm{NH}_{4} \mathrm{H}_{2} \mathrm{PO}_{4}$ (ADP), potassium dihydrogen phosphate $\mathrm{KH}_{2} \mathrm{PO}_{4}(\mathrm{KDP})$ and potassium dideuterium phosphate $\mathrm{KD}_{2} \mathrm{PO}_{4}$ (heavy water KDP). $\mathrm{V}_{\lambda / 2}$ is the voltage necessary for a $90^{\circ}$ rotation of the plane of polarization. Figure 3 shows the results, according to which $V_{\lambda / 2}$ assumes the smallest values in heavy water KDP. The half-wave length voltage depends almost linearly on the wave length, being smaller in the blue than in the red. At the wave length $\lambda=546.1 \mathrm{~m} \mu$, $v_{\lambda / 2}$ is:

ADP
9.4 kv

KDP
7. 7 kv

KDP (heavy water) 3.4 kv


Figure 3. Half-wave length voltages $\mathrm{V}_{2 / 2}$ of $\mathrm{NH}_{4} \mathrm{H}_{2} \mathrm{PO}_{4}, \mathrm{KH}_{2} \mathrm{PO}_{4}$, and $\mathrm{KD}_{2} \mathrm{PO}_{4}$ as a function of wave length.
(3) determined the cutting direction for optimum separation of the ordinary and extraordinary rays in calcite as shown in Figure 4. The angle between the rays, $\epsilon_{\text {max }}$ for calcite is approximately $6^{\circ}$. This angular separation indicates that calcite is a satisfactory birefringent crystal for use in the digital light deflector.


Figure 4. Orientation of calcite crystals for maximum splitting of ordinary and extraordinary rays.

Looking forward to a deflector utilizing convergent light beams we:
(4) calculated the relation between the maximum number of resolvable positions and aperture of the deflector due to diffraction as shown in Figure 5. This calculation indicates that a 1000 position linear digital light deflector is feasible without requiring too large crystals.


Figure 5. Minimum aperture, a, of the convergent beam deflector for N resolvable spots.
(5) calculated the minimum spot size 8 with relation to the number of resolvable spots (Figure 6) for a convergent beam deflector of aperture, $a=1.2 \mathrm{~cm}$. Die to diffraction at the aperture, the spot size will be approximately $30 \mu$ for a field of 256 resolvable spots.
(6) investigated compensation of angular birefringence in KDP crystals employing a $90^{\circ}$ rotation quartz crystal arranged between two properly oriented KDP crystals. ${ }^{1}$ Figure 7 shows the zero field transmission of the compensated electro-optic switch as a function of incidence angle of light. Compensation is essential in deflectors utilising convergent beams aince, without compensation, only collimated beams directed parallel to the optic axis find no birefringence in unswitched KDP crystals.

\author{

1. Wiley, C. A., U. S. Patent 2, 780, 958, December 1950.
}


Figure 6. Minimum spot size of a convergent beam deflector having a 1.2 cm aperture.


Figure 7. Compensation of angular birefringence.

## Calculation of maximum splitting angle in an optically birefringent cryatal

## The following symbols apply to Figure 8.

IE principal section (X-Z plane) through the index ellipsoid of a birefringent crystal
$\lambda$ angle between the normal on the crystal and the $Z$ axis of the index ellipsoid

LO light beam - normally incident on the surface of the crystal
OA path of the ordinary ray within the crystal
OE path of the extraordinary ray within the crystal, which according to theory of crystal optics is parallel to $T$
$\varepsilon$
ON direction of oscillation of the $D$ vector of the extraordinary ray. The length of $\mathrm{O}-\mathrm{N}$ is equal to the index of the refraction n of the extraordinary ray. Due to the normal incidence of LO, ON lien in the surface of the crystal

T
Tangent on IE at N


Figure 8. Calculation of maximum aplitting angle.

The equation of the index ellipsoid is $\frac{x^{2}}{n_{0}^{2}}+\frac{z^{2}}{n_{e}^{2}}=1$
It yields for $T$

$$
\tan \delta=-\left(\frac{n_{e}}{n_{0}}\right)^{2} \frac{x}{z}=\left(\frac{n_{e}}{n_{0}}\right)^{2} \frac{1}{\tan \gamma}
$$

Therefore

$$
\varepsilon=\gamma+\delta-\frac{\pi}{2}=\gamma+\arctan \left[\left(\frac{n_{e}}{n_{0}}\right)^{2} \frac{1}{\tan \gamma}\right]-\frac{\pi}{2}
$$

The maximum condition $\frac{\partial \varepsilon}{\partial \gamma}=0$ yields for $\varepsilon_{\max }$

$$
\varepsilon_{\max }=\arcsin \frac{n_{e}}{\sqrt{n_{e}^{2}+n_{0}^{2}}}+\arctan \left(\frac{n_{e}}{n_{0}}-\frac{\pi}{2}\right)
$$

## Calculation of the relation between the numbers of positions and the aperture of a digital deflector, for convergent beams

In Figure 9, the following symbols are used:
a. input aperture of the deflector
s space necessary for each electro-optic rotator
$\Delta \quad$ thickness of the first calcite crystal
$n \Delta \quad$ thickness of the nth calcite crystal
8 diameter of the first order diffraction ring
$\alpha \quad$ diffraction angle
L total length of the deflector
n number of stages
N number of resolvable spots


Figure 9. Diffraction problem in the digital deflector.

In calcite crystals, the splitting angle between the two rays is $\approx 6^{\circ}$. The separation of outputs therefore is $\Delta \cdot \frac{\pi}{180} \cdot 6 \approx \frac{\Delta}{10}$. For a good resolution of neighboring spots, it is assumed $\frac{\Delta}{10}=1.338$.
Starting with

$$
L=n \cdot s+\sum_{\nu=1}^{n} 2^{v-1} \Delta=n \cdot s+\left(2^{n}-1\right)
$$

and the relation for the first order diffraction minimum

$$
L=\frac{\delta}{2 \sin \alpha} \approx \frac{8 \mathrm{a}}{2 \lambda}
$$

one finds the minimum spot size is:

$$
\delta=\frac{n \cdot s}{\frac{a}{2 \lambda}-13.3\left(2^{n}-1\right)}
$$

The curve of Figure 6 is calculated for $=3 \mathrm{~cm}$ apace for each electrooptic switch, an aperture $a=1.2 \mathrm{~cm}$ and a wave length $\lambda=546.1 \mathrm{~m} \mu$.

The minimum aperture, $a$, for N resolvable spots can be calculated from the above equation by setting the aperture, a, equal to the space needed for the $N$ resolved spots:

$$
1.338 \cdot 2^{n}=a
$$

This yields

$$
a=13.3\left(2^{n}-1\right) \lambda\left[1+\sqrt{1+1.5 \cdot 10^{-2} \cdot \frac{8 \cdot n}{\lambda\left(2^{n / 2}-2^{-n / 2}\right)^{2}}}\right] .
$$

The curve of Figure 5 is calculated for $s=3 \mathrm{~cm}$ and $\lambda=546.1 \mathrm{~m} \mu$

## CONICAL REFRACTION

## General

Conical refraction was originally predicted theoretically in 1832 in Hamilton $^{2}$ and experimentally confirmed by Lloyd ${ }^{2}$ in 1833. An infinite number of possible propagation directions of irradiated light exists in conical refraction. These directions form a cone in the crystal. Incident polarized light leaves the crystal with a $\cos ^{2}$ distribution of intensity on the periphery of a cylinder. The locus of maximum light intensity depends on the polarization direction of incoming light and therefore can be controlled electrically by the aid of an electro-optic rotator (Figure 10). The relatively low resolution of this deflectable $\cos ^{2}$ distribution can be improved to a $\cos ^{4}$ distri- $^{\text {dis }}$ bution by the aid of a second identical electro-optic rotator (Figure 11 and Appendix I). Additional improvement can be obtained by the combination with other analog deflectors of higher resolution which need some predeflection

[^0]

Figure 10. Light deflection by conical refraction.


Figure 11. Improved light deflection by conical refraction.
of the beam to yield a useful light intensity. Our prime motivation for investigating conical refraction is to explore its usefulness in an analog light deflection system, but in addition there are uncertainties related to a basic understanding of the phenomenon.

Accomplishments
As part of our work in the first quarter reporting period on conical. refraction, we calculated (Appendix II) the cone angle $E$ of several materials:
Anthracene $\quad 18^{\circ} 30^{\prime}$

Naphthalene $\quad \mathbf{1 3 0}^{\mathbf{0}} \mathbf{4 2}$
Hydrocarbostyril $\quad 10^{\circ} 56^{\prime}$
Naphthalene disulfonic acid $\quad 10^{\circ} 17^{\prime}$

Stilbene $\quad 3^{\circ} 49^{\prime}$
Aragonite $\quad \mathbf{1 0 4}^{\mathbf{0}}{ }^{\prime}$
Turquoise $\quad 1^{\circ} 9^{\prime}$
Topaz $0^{\circ} 11^{\prime}$
On the basis of the table, and availability of materials, we are investigating anthracene, napthalene, and aragonite.

We contacted Harshaw Chemical Co., Isomet Corp. and Semielements, Inc. for single crystals of suitable materials. Although we succeeded in getting naphthalene crystals, these crystals exhibited some unfavorable properties such as unsatisfactory optical quality and high vapor pressure.

The major part of this quarter's effort on conical refraction was devoted to:
a) surface protection
b) cutting, grinding, and polishing naphthalene crystals
c) orienting naphthalene crystals for optic axis determination
d) calculating an improved electro-optic analog light deflector wiring conical refraction

We succeeded in finding the optic axes and obtaining conical refraction in crystal slices approximately 0.3 mm thick. Pin hole diaphragms had to be used to detect the output circle at this thickness. These diaphragms did not permit collimation of the input beam. We have not, as yet, succeeded in obtaining conical refraction with thicker naphthalene plates. Since this is partly due to the unsatisfactory optical quality of these crystals, we have begun a review of other possible materials.

## ELECTRICALLY CONTROLLED FRESNEL ZONE LENS

If normal light is passed through a grating the periodicity of which is in the order of some hundreds of millimeters, the light will be diffracted at this grating. In certain directions, the light will interfere constructively, in other directions destructively so that the light leaves the grating diffracted in certain directions.

A Fresnel zone lens is a concentric grating the periodicity of which varies with the distance from the center. The boundaries between lines and slits are called zones. If the radius of the $m$-th zone is

$$
r_{m}=\sqrt{m f \lambda}
$$

(whore $\lambda$ is the wave length of light), the collimated light passing through the plate is focussed to a point at the axis at a distance, f, from the plate. This action of a Fresnel zone lens is described in more detail by others. ${ }^{3,4}$ The basic idea of the Fresnel zone lens of this contract is shown in Figure 12. An electro-optic active crystal (e.g. a KDP crystal) is oriented so that the


Figure 12. Electrically controlled Fresnel zone lens.

3 R. S. Longhurst, Geometrical and Physical Optics, Wiley, 1962, p. 261 ff.
incident collimated light - which is also linearly polarized - passes through this crystal in the direction of its optic axis. To the front and back surface of the crystal are attached bands of transparent electrodes the spacing of which is according to that of Fresnel zones. An electric voltage $V_{\lambda / 2}$ can be applied to these electrodes. This effects the crystal to become birefringent in the areas between opposite electrodes so that the plane of polarization of the light passing through this area is rotated for $90^{\circ}$.

The action of the Fresnel zone plate is the following: If no voltage is applied to the electrodes the incident light finds an isotropic plate through which it passes uneffected. After application of the voltage $V_{\lambda / 2}$ the light which passes through the electrode areas experiences $90^{\circ}$ rotation of its plane of polarization. Therefore this light no longer is capable of interfering with the light which has passed through areas not covered by the electrodes. Thus, the rotated and the not rotated parts of the light beam each act as the light in a normal Fresnel lens: they are focussed to the focal point.

A variation of this principal idea comprises the use of opaque electrodes. In a similar arrangement like that of Figure 12, either no light is transmitted or the light is focussed. Other variations comprise effects arising if the applied voltage is varied continuously.

During this quarterly reporting period we:
(1) tried to get a pattern of five opaque electrode bands. Photo-etched copper plates were used as masks for vacuum deposition. The evaporated electrode pattern, however, was too blurred at the edges to be useful.
(2) we calculated the zone radii for the first 100 zones for $f=30 \mathrm{~cm}$ and $\mathrm{f}=50 \mathrm{~cm}$ focal length. For exact values this work was done by our computer dept. The results are shown in Table I and II and indicate the minute work to be spent for ti.e electrodes.
(3) we are now examining the feasibility of photo-etching glass substrates to produce the fine resolution electrode structure required for a 50 zone-electrode Fresnel lens.

As is evident from the description of our activity on the Fresnel lens, our major problem is to obtain an electrode structure with sufficient precision to produce a good focusing action.

Table 1. Zone radii of Fresnel lens for $f=30 \mathrm{~cm}$ at $\lambda=546.1 \mathrm{~m} \mu$.

| Zone <br> Number | Radius (cm) | Zone Numb | Radius (cm) | Zone Number | Radius (cm) |
| :---: | :---: | :---: | :---: | :---: | :---: |
| 1 | 0.0404759 | 36 | 0. 2428555 | 71 | 0.3410562 |
| 2 | 0.0572416 | 37 | 0. 2462054 | 72 | 0. 3434496 |
| 3 | 0.0701063 | 38 | 0. 2495103 | 73 | 0.3458264 |
| 4 | 0.0809518 | 39 | 0. 2527720 | 74 | 0.3481870 |
| 5 | 0.0905069 | 40 | 0.2559922 | 75 | 0.3505317 |
| 6 | 0.0991453 | 41 | 0.2591723 | 76 | 0.3528609 |
| 7 | 0.1070892 | 42 | 0.2623139 | 77 | 0.3551747 |
| 8 | 0.1144832 | 43 | 0.2654183 | 78 | 0.3574736 |
| 9 | 0.1214278 | 44 | 0. 2684869 | 79 | 0.3597578 |
| 10 | 0.1279961 | 45 | 0.2715207 | 80 | 0.3620276 |
| 11 | 0. 1342434 | 46 | 0. 2745210 | 81 | 0.3642833 |
| 12 | 0.1402127 | 47 | 0.2774889 | 82 | 0. 3665250 |
| 13 | 0.1459380 | 48 | 0.2804254 | 83 | 0.3687532 |
| 14 | 0.1514470 | 49 | 0.2833314 | 84 | 0.3709679 |
| 15 | 0.1567626 | 50 | 0. 2862080 | 85 | 0.3731695 |
| 16 | 0. 1619037 | 51 | 0. 2890559 | 86 | 0. 3753582 |
| 17 | 0. 1668865 | 52 | 0.2918760 | 87 | 0.3775342 |
| 18 | 0.1717248 | 53 | 0. 2946691 | 88 | 0.3796978 |
| 19 | 0.1764304 | 54 | 0.2974360 | 89 | 0.3818491 |
| 20 | 0. 1810138 | 55 | 0. 3001774 | 90 | 0. 3839883 |
| 21 | 0. 1854840 | 56 | 0. 3028940 | 91 | 0. 3861157 |
| 22 | 0.1898489 | 57 | 0. 3055865 | 92 | 0. 3882314 |
| 23 | 0.1941157 | 58 | 0. 3082554 | 93 | 0.3903356 |
| 24 | 0.1982907 | 59 | 0.3109014 | 94 | 0.3924286 |
| 25 | 0.2023796 | 60 | 0.3135251 | 95 | 0.3945105 |
| 26 | 0. 2063875 | 61 | 0.3161270 | 96 | 0. 3965814 |
| 27 | 0.2103190 | 62 | 0.3187077 | 97 | 0. 3986416 |
| 28 | 0.2141784 | '3 | 0.3212676 | 98 | 0.4006912 |
| 29 | 0.2179695 | 64 | 0.3238073 | 99 | 0.4027303 |
| 30 | 0.2216957 | 65 | 0.3263273 | 100 | 0.4047592 |
| 31 | 0.2253604 | 66 | 0. 3288279 |  |  |
| 32 | 0.2289664 | 67 | 0.3313097 |  |  |
| 33 | 0.2325164 | 68 | 0.3337730 |  |  |
| 34 | 0.2360131 | 69 | 0.3362182 |  |  |
| 35 | 0.2394588 | 70 | 0. 3386458 |  |  |

Table II. Zone radii of Fresnel lens for $f=30 \mathrm{~cm}$ at $\lambda=546.1 \mathrm{~m} \mu$.

| Zone Number | Radius (cm) | Zone Number | Radius (cm) | Zone Number | Radius (cm) |
| :---: | :---: | :---: | :---: | :---: | :---: |
| 1 | 0.0522542 | 36 | 0.3135251 | 71 | 0.4403016 |
| 2 | 0.0738986 | 37 | 0.3178498 | 72 | 0.4433915 |
| 3 | 0.0905069 | 38 | 0.3221164 | 73 | 0.4464600 |
| 4 | 0. 1045084 | 39 | 0.3263273 | 74 | 0.4495075 |
| 5 | 0. 1168439 | 40 | 0.3304845 | 75 | 0.4525345 |
| 6 | 0.1279961 | 41 | 0.3345900 | 76 | 0.4555414 |
| 7 | 0.1382516 | 42 | 0. 3386458 | 77 | 0.4585286 |
| 8 | 0.1477972 | 43 | 0. 3426536 | 78 | 0.4614965 |
| 9 | 0. 1567626 | 44 | 0.3466151 | 79 | 0.4644454 |
| 10 | 0. 1652422 | 45 | 0.3505317 | 80 | 0.4673757 |
| 11 | 0.1733075 | 46 | 0.3544051 | 81 | 0.4702877 |
| 12 | 0.1810138 | 47 | 0.3582366 | 82 | 0.4731818 |
| 13 | 0. 1884051 | 48 | 0.3620276 | 83 | 0.4760583 |
| 14 | 0.1955173 | 49 | 0. 3657793 | 84 | 0.4789175 |
| 15 | 0.2023796 | 50 | 0. 3694929 | 85 | 0.4817598 |
| 16 | 0.2090167 | 51 | 0. 3731695 | 86 | 0.4845854 |
| 17 | 0. 2154495 | 52 | 0.3768103 | 87 | 0.4873946 |
| 18 | 0.2216957 | 53 | 0.3804162 | 88 | 0.4901877 |
| 19 | 0.2277707 | 54 | 0. 3839883 | 89 | 0.4929650 |
| 20 | 0. 2336878 | 55 | 0. 3875274 | 90 | 0.4957267 |
| 21 | 0. 2394588 | 56 | 0.3910345 | 91 | 0.4984732 |
| 22 | 0. 2450939 | 57 | 0. 3945105 | 92 | 0.5012045 |
| 23 | 0.2506023 | 58 | 0.3979560 | 93 | 0.5039211 |
| 24 | 0.2559922 | 59 | 0. 4013720 | 94 | 0.5066231 |
| 25 | 0.2612709 | 60 | 0. 4047592 | 95 | 0.5093108 |
| 26 | 0. 2664451 | 61 | 0.4081182 | 96 | 0.5119844 |
| 27 | 0.2715207 | 62 | 0.4114499 | 97 | 0.5146440 |
| 28 | 0.2765032 | 63 | 0.4147547 | 98 | 0.5172900 |
| 29 | 0. 2813974 | 64 | 0.4180335 | 99 | 0.5199226 |
| 30 | 0. 2862080 | 65 | 0.4212867 | 100 | 0.5225419 |
| 31 | 0. 2909390 | 66 | 0.4245150 |  |  |
| 32 | 0. 2955943 | 67 | 0.4277189 |  |  |
| 33 | 0. 3001774 | 68 | 0.4308991 |  |  |
| 34 | 0.3046916 | 69 | 0.4340559 |  |  |
| 35 | 0. 3091399 | 70 | 0.4371899 |  |  |

## CONC LUSIONS

On the basis of our work during this quarterly reporting period, we have arrived at the following conclusions:
a. Digital light deflection by means of a combination of electro-optic switches and passive birefringent crystals has shown promise of meeting our performance expectations for practical display and printing apparatus using optical masers as the high-intensity light source.
b. Conical refraction is a difficult phenomenon to work with, but nevertheless shows promise for those applications requiring analog control of deflections.
c. An electrically controlled focus/defocus lens employing the Freanel zone plate principle requires fine detail in its electrode construction, but is promising as an amplitudemodulation device for optical masers.
d. We have decided to devote our major efforts to the design and construction of the digital light deflector during the next quarter of the contract.

PUBLICATIONS, LECTURES, REPORTS, AND CONFERENCES CONFERENCES

A conference was held 25 January 1963 at Fort Monmouth, New Jersey between Messrs. W. Huber, and D. Bonda at Fort Monmouth and Messrs. J. Ballance, D. A. Raunick and H. Fleisher of IBM to review the work to date and discuss future plans on the Laser study. Dr. Fleisher indicated, and Messrs. Huber and Bonda agreed that at a later date it may be desirable to change direction -- especially in the deflections study.

A conference was held on February 6, 1963 at IBM, Poughkeepsie, New York between Mr. Bonda at Fort Monmouth and Messers H. Fleisher and D. Raunick of IBM. Mr. Bonda reviewed the monthly letter report format and met the personnel assigned to work on this contract. Dr. Fleisher conducted a tour of the laser laboratories and demonstrated two basic experiments which have been set up under the contract.

PATENTS REDUCED TO PRACTICE
Docket No: 7662
Title: "A Digital Index Electro-Optic Light Beam Deflection System"
Inventors: W. Kulcke and T. J. Harris

## KEY PERSONNEL

The following key personnel are directly assigned to this contract:

| Name | Title | Approximate M <br> worked on this |
| :--- | :--- | :--- |
| Dr. Harold Fleisher | Senior Physicist | 130 |
| Dr. Werner Kulcke | Physicist | 240 |
| Kurt Kosanke | Physicist | 240 |
| William Robinson, Jr. | Senior Associate Engineer | 16 |
| Werner Schneider | Technician | 240 |

an-hoursDr. Werner KulckePhysiaist240
Kurt KosankeSenior Associate Engineer16
Werner Schneider Technician ..... 240

Resume data for each of the key personnel follows.

## HAROLD FLEISHER

Dr. Fleisher is the manager of IBM's Electro-Optice Laboratory, Poughkeepsie, New York. This contract is under his immediate direction and supervision. He has been a research physicist and senior engineer at various academic institutions and industrial companies. He has managed many technical and administrative groups at IBM, has written many technical articles, and has contributed chapters to cientific and technical books. He holds several patents and many disclosures. In list form, Dr. Fleisher's wide technical and scientific background and accomplishments are:

1. Research Assistant in Physics Department and Institute of Optics during 1942-1943, University of Rochester.
2. Staff Member, Radiation Laboratory, Massachusetts Institute of Technology, during 1943-1946.
3. Senior Engineer, Rauland Corporation, Chicago, Illinois, during 1946.
4. Instructor at the Case Institute of Technology during 1946-1950.
5. Physicistat International Business Machines Corporation (Engineering Laboratories), Poughkeepsie, New York. Worked on transistor research and development, 1950-1956.
6. Manager of Research Communications 1956-1958, IBM Research Laboratory.
7. Manager, Theory of Machine Organization, IBM Research Laboratory, 1959 to September 1961.
8. Manager, Exploratory Electro-Optics (present).

Education
BA (Physics) University of Rochester (1942)
MS (Physics) University of Rochester (1943)
PhD (Physics) Case Institute of Technology (1951)

## Papers

1. Chapter 10 in Volume 18, "Vacuum Tube Amplifiers" Radiation Laboratory Series.
2. Two chapters in Handbook of Semi-Conductor Electronics.
3. Articles on graphical analysis of transistor, published in Proceedinge of IRE; and on Information Theory, published in Library Quarterly.
4. Currently working on book on Logic and Switching.
5. Internal Technical Reports.

Patents and Disclosures
Four patents on switching circuits and 21 disclosures.
Societies (Member)
American Physical Society, Sigma $X_{i}$ and RESA; Institute of Radio Engineers; Institute of Symbolic Logic; American Mathematical Society.

## Honors

Turnbull Fellowship at Case Institute of Technology.
Listed in American Men of Science; Industrial Who's Who.

## WERNER KULCKE

Dr. W. Kulcke does theoretical and experimental work for the control of light. Previously, Dr. Kulcke was manager of the Electro-Optics project at the German IBM Laboratories in Boeblingen. At the German Laboratory he worked on problems of polarization optical logic, electro-optic measurements in ferroelectric crystals, and he supervised the construction of the feasibility model of a very high speed electro-optic character generator.

Before joining IBM he worked on X -ray investigations of the structures of amorphous selenium at the T. H. Stuttgart/Germany and he developed a radio-sonde for measurement of the ozone content of the upper atmosphere at the Max-Planck Institute for Physics of the Stratosphere. The latter work was done for the International Geophysical Year 1956-57 and the apparatus is now used by the U.S. Weather Bureau.

## Education

Diploma in Physics T. H. Stuttgart/Germany
Thesis - Max-Planck Institute for Physics of the Stratosphere
Werssenau/Germany
Dr. ver. nat. T. H. Stuttgart/Germany
Patents and Disclosures
One patent and 11 disclosures.
Papers
Two papers on Physics of the upper atmosphere and X-ray analysis, published in German Journals.

Three technical reports and 5 laboratory reports on different electro-optic subjects.

Memberships
Member of the Germany Physical Society.

## KURT KOSANKE

Mr. Kosanke, received a thorough training in the design and fabrication of optical instruments while working for the I. D. Moeller Company in Germany before returning to school. After graduating with an Engineer of Physics degree from the Physics Techn. Lehranstalt, Luebeck, Mr. Kosank joined IBM, Germany. There he first attended a training course on IBM machines and was subsequently assigned to working on the electro-optic effect in crystals in the IBM Laboratories in Germany.

Mr. Kosanke recently transferred to the IBM Data Systems Laboratory in the United States to continue working in electro-optics effects and devices.

## Education

Engineer of Physics, Physics Techn. Lehranstalt, Luebeck, Germany. Patent Disclosures

2

## Papers

2 IBM reports pertaining to electro-optic effects and devices.
Memberships
VDI (Verein Deutscher Ingenieure) Germany

WILLIAM J. ROBINSON, JR.
Mr. Robinson work in the IBM Data Systems Division Optics Laboratory involves the specifications and alignment of all optics equipment. He sets up and assists in the optics experiments for the study of laser output and laser application. Mr. Robinson has had extensive experience in optics. As Optical Engineer for Autometric Corporation he was engaged in the alignment of optics in Zenith Star camera, Uniscale Matcher Photogrammetric apparatus and preliminary "mock-ups" of optical radar restitutor and other photogrammetric instruinents.

At the Perkin-Elmer Corporation he conducted the alignment of Optical Reference for missile firing system in nuclear submarines; conducted ! studies of human cornea. plotter for the research department; planned overall optical testing facilities and photographic darkrooms for a new engineering
building. He aligned the optical readout system for ROTI missile tracking telescope at White Sands Missile Range; and conducted distortion measurements of "Geocon" aerial camera lenses.

He was the Resident Engineer for Cape Canaveral Optics, handling problems concerned with all optical and photographic equipment at Cape Canaveral and outlying camera stations. Cared for all optical engineering problems relating to cameras, lenses, tracking mounts and allied facilities.

At Patrick Air Force Base (Cape Canaveral), Mr. Robinson was in the Quality Analysis group for the investigation of optical tracking data and the study of optical instrumentation errors.

At Arma Corporation, he was engaged in optical engineering on problems relating to the manufacturing of the $T-41$ stereoscope range finder for medium tanks. He worked on the development and design of test equipment through test-to-production stage of program.

At the Zoomar Corporation, Mr. Robinson was engaged in the development and field engineering of special effects lenses and related devices for motion picture and television cameras.

At Western Union, he was in charge of applications investigations for the Western Union Concentrated Arc Lamp (Zirconium Arc) and other byproducts of Western Union Research.

While in the Army, Mr. Robinson served as Research Assistant in Instrumentation, interpreatation of data and the development of theory on the tropical environments atudies ataff of laboratory, and was in charge of statistical group.

As Development Engineer for Westinghouse, he was engaged in research and development in problems relating to manufacture of incandescent, fluorescent and vapor lamps, quality control problems, instrumentation and adaption to manufacture. Conducted special investigation on lamps for the armed forces.

Also, Mr. Robinson has served as a consultant in Optical Instrumentation for Sloan-Kettering Institute for Cancer Research, Edmund Scientific Corporation, and Star-Fuse Company, Inc.

## Education

AB (Physics) Washington Missionary College (1942)
Electronics, Columbia University (1943-3)
Graduate Research Management, New York University (1949-50)

## Papers

Rough Service Electrical Device -- U. S. Patent \#2, 398,595
Publications in: New York Times; Popular Science; Scientific American;
Time; Life; Graphic Arts.
Lectures
"On Zirconium Arc"

To: New York Section, Technical Division, Photographic Society of America; Biological Photographers Association, National Convention; Alpha Chi Sigma Fraternity (Chemista), New York Chapter.

## Professional Societies

## Optical Society of America (member)

Technical Division, Photographic Society of America (Member and Chairman) National Scholarship Committee (Member)

## Honors

Certificate of Honor - New York Section, Technical Division, Photographic Society of American (1952)

## WERNER SCHNEIDER

Mr. Schneider is presently engaged in the IBM Data Systems Division Optics Laboratory. According to his experiences he works on design and construction of the needed apparatus suggested in this project and he assists in the conduction of experiments.

Before joining IBM Mr. Schneider worked in the Daimler Benz AG, Sindelfingen, Germany on electronic control of machines for automobile manufacture. He joined IBM December 1960 and has worked since then on CdSe photo conductors, parts for the electronic control of the electrooptic high-speed printer, and on the growth of water soluble electro-optic active crystals (KDP, ADP).

Education
Technician Techn. Lehrinstitut, Weil/Rhein, Germany.

## APPENDIX 1.

## Calculation of Improved Electro-Optic Light Deflector Utilizing Conical Refraction

The elements of the improved light deflector are shown in Figure 13. The electric vector for incoming light from the left of the diagram is split into components as shown. Changes of components of the light as they occur in the elements of the deflector are calculated. The status of polarization with respect to the selected coordinates is also shown. The components of the electric vector $E$ of the light are described below as the light leaves the element:
(1) Polarizer
$E_{x}=0$ and $E_{y}=E_{0} \sin \omega t$
(2) KDP Crystal
( $\psi=$ phase retardation produced by voltage $v$ )
$E_{x^{\prime}}=-1 / 2 \sqrt{2} E_{0} \sin (\omega t+\psi)$ and $E_{y^{\prime}}=1 / 2 \sqrt{2} E_{0} \sin \omega t$
Therefore eliptically polarized light is obtained.
(3) Quarter Wave Plate
$E_{x}=\sqrt{1 / 2(1-\cos \psi)} E_{0} \sin (\omega t+\psi / 2)$ and $E_{y}=\sqrt{1 / 2(1+\cos \psi)} E_{0} \sin (\omega t+\psi / 2)$
Linearly polarized light, direction of polarization rotated for $\varphi=\boldsymbol{\varphi} / 2=$
$\frac{\pi}{2} \frac{v}{v_{\lambda / 2}}$
(4) Crystal with conical refraction
$E(\varphi, \theta)=E_{0}^{\prime} \cos (\theta-\varphi) \sin (\omega t+\varphi)$
Therefore, the intensity $I(\varphi, \theta)=I_{0}^{\prime} \cos ^{2}(\theta-\varphi) \sin ^{2}(\omega t+\varphi)$ which is the $\cos ^{2}$ distribution.
(5) Quarter Wave Plate

$$
\begin{aligned}
& E_{x}(\varphi, \theta)=E_{0}^{\prime} \sin \theta \cos (\theta-\omega) \cos (\omega t+\varphi) \\
& E_{y}(\varphi, \theta)=E_{0}^{\prime} \cos \theta \cos (\theta-\omega) \cos (\omega t+\varphi)
\end{aligned}
$$

(6) KDP Crystal

$$
\begin{aligned}
& E_{x^{\prime}}(\varphi, \theta)=-1 / 2 \sqrt{2} E_{0}^{\prime} \cos (\theta-\varphi) \sin [\omega t-(\theta-\varphi)] \\
& E_{y^{\prime}}(\varphi, \theta)=1 / 2 \sqrt{2} E_{0}^{\prime} \cos (\theta-\varphi) \sin [\omega t+(\theta-\varphi)]
\end{aligned}
$$

(7) Polarizer
$E_{x}=0$
$E_{y}=E_{0}^{\prime} \cos ^{2}(\theta-\varphi) \sin \omega t$
or the intensity
$I(\varphi, \theta)=I_{0}{ }^{\prime} \cos ^{4}(\theta-\varphi) \sin ^{2} \omega t$
The light leaving the deflector has a distribution of intensity as $\cos ^{4}(\theta, \varphi)$, with the maximum intensity at $\theta=\varphi$.


ELEMENT: 1
2
3
4
5
6
7

COORDIMATES:


Figure 13. Calculation of improved electro-optic light deflector.

## Calculation of the Cone Angle $\xi$ of Conical Refraction

Referring to Figure 14, the cone angle, $\}$, is found in the $\mathrm{X}-\mathrm{Z}$ plane of the index ellipsoid. It is the angle between the optic axis OA and the line OP; therefore

$$
\xi=\mathrm{V}-\mathrm{w}
$$



Figure 14. Calculation of cone angle $\xi$.

OP is the propagation direction of a beam having its wave normal parallel to the optic axis and being polarized in the $X-Z$ plane. Its polarization direction ON is perpendicular to its wave normal OA. According to the theory of crystal optics the direction of propagation OP is parallel to the tangent to the index ellipsoid at N .

If $n_{1}, n_{I I}, n_{\text {III }}$ are the principal axes of the index ellipsoid, the angle $V$ between the $Z_{\text {and the optic axis is }}{ }^{5}$

$$
\tan V=\sqrt{\frac{\frac{1}{n_{I}^{2}}-\frac{1}{n_{I I}^{2}}}{\frac{1}{n_{H I}^{2}} \frac{1}{n_{H I}^{2}}}}
$$

With $\tan W=\frac{n_{I}^{2}}{n_{I I I}^{2}} \quad \tan V, \quad$ becomes

$$
\xi=\arctan \sqrt{\frac{\frac{1}{n_{1}^{2}}-\frac{1}{n_{I I}^{2}}}{\frac{1}{n_{I I}^{2}}-\frac{1}{n_{I I I}^{2}}}} \quad-\arctan \frac{n_{1}^{2}}{n_{I I I}^{2}} \sqrt{\frac{\frac{1}{n_{I}^{2}}-\frac{1}{n_{I I}^{2}}}{\frac{1}{n_{I I}^{2}}-\frac{1}{n_{I I I}^{2}}}}
$$

OASD (R\&E), Rm 3E1065
ATTN: Technical Library
The Pentagon
Washington 25, D.C. ..... 1
Chief of Research and Development OCS, Department of the Army
Washington 25, D.C. ..... 1
Commanding General
U. S. Army Materiel Command
ATTN: R\&D Directorate
Washington 25, D. C. ..... 1
Commanding General
U. S. Army Electronics Command
ATTN: AMSEL-AD
Fort Monmouth, N.J. ..... 3
Commanding General
USA Combat Developments Command
ATTN: CDOMR-E
Fort Belvoir, Virginia ..... 1
Commanding General
U.S. Army Materiel Command
ATTN: AMCRD-RS-PE, Mr. A. Maklin
Bldg. T-17, Gravelly Point, Virginia ..... 1
Commander,
Armed Services Technical Information Agency ATTN: TISIA
Arlington Hall Station Arlington 12, Virginia ..... 10
Commanding Officer
USA Communication \& Electronics Combat Development Agency Fort Huachuca, Arizona ..... 1
Commanding Officer
U.S. Army Electronics Materiel Support Agency ATTN: SELMS-ADJ
Fort Monmoith, New Jersey ..... 1
Commanding Officer
U.S. Army Electronics Research \& Development Laboratory ATTN: Logistics Division Fort Monmouth, New Jersey (MARKED FOR PROJECT ENGINEER)
Commanding Officer
U. S. Army Electronics Research \& Development Laboratory ATTN: Director of Research/Engineering Fort Monmouth, New JerseyCommanding OfficerU. S. Army Electronics Research \& Development LaboratoryATTN: Technical Documents Center
Fort Monmouth, New Jersey ..... 1
Commanding Officer
U. S. Army Electronics Research \& Development LaboratoryATTN: SELRA/NP-4
Fort Monmouth, New Jersey ..... 1
Commanding Officer
U. S. Army Electronics Research \& Development Laboratory
ATTN: Dr. E. A. Gerber
Director of Solid State \&Frequency Control Division (PF)
Fort Monmouth, New Jersey1
Command Officer
U. S. Army Electronics Research \& Development LaboratoryATTN: Dr. H. S. Bennett
Communications Dept (NO-4)
Fort Monmouth, New Jersey1
Commanding Officer
U. S. Army Electronics Research \& Development LaboratoryATTN: Technical Information Division
Fort Monmouth, New Jersey (Unclassified Reports Only) ..... 3
(FOR RETRANSMITTAL TO ACCREDITED BRITISH \& CANADIAN GOVERN-MENT REPRESENTATIVES)
Commanding Officer
Hqs. Rome Air Development Centcr
Research \& Technology Division
ATTN: RASGD/M. Kesselman
Air Force Systems Command
U. S. Air Force
Griffiss Air Force Base, N. Y.
Commanding Officer and Director
U. S. Navy Electronics Laboratory
San Diego 52, California ..... 1
Chief, U. S. Army Security Agency
Arlington Hall Station
Arlington 12, Virginia ..... 2
Deputy President
U. S. Army Sécurity Agency Board
Arlington Hall Station
Arlington 12 , Virginia ..... 1
Director, U. S. Naval Research Laboratory
ATTN: Code 2027
Washington 25, D.C. ..... 1
Director, Fort Monmouth Office
USA Communication \& Electronics Combat Development Agency Fort Monmouth, New Jersey ..... 1
Air Force Cambridge Research Laboratories
ATTN: CRZC
L. G. Hanscom Field
Bedford, Massachusetts1
Air Force Cambridge Research Laboratories
ATTN: CRXL-R
L. G. Hanscom Field
Bedford, Massachusetts ..... 1
Hq, Electronic Systems Division
ATTN: ESAT
L. G. Hanscom FieldBedford, Massachusetts1
Rome Air Development Center
AT'TN: NAALD
Griffics Ai: Forve Base, New York ..... 1
AFSCScientific/Technical Liaison Office
U. S. Naval Air Development Center Johnsville, Peansylvania ..... 1
Corps cf Fingineers Liaison Office
U. S. Ainny Electronics Research \& Development Laboratory For: iNonmouth, New JerseyMarir- Corpu Liaison OfficeU. S. Army Electronics Research \& Development LaboratoryFort Monmouth, New Jersey1
Ay SC Scientific/Technical Liaison Office
'J. S. Army Electronics Research \& Development Laboratory Firt Monmouth, New Jersey ..... 1
Dr. Selig Starr
Office of Chief of Research \& Development
Department of the Army
Washington 25, D.C.1
Mr. Lewis R. Blair, Jr.
Television and Electronic Display Div.
Audio Visual Comm. Directorate
Office Chief Signal Officer
Room 5A466, The Pentagon
Washington 25, D.C. ..... 1
Dr. C. A. Rosen
Applied Physics Laboratory
Stanford Research Institute Menlo Park, California ..... 1

| AD UNCLASSIFIED | AD UNCLASSIFIED |
| :---: | :---: |
| Development Lab., International Business Machines, Poughkeepsie, N. Y. USE OF OPTICAL MASERS IN DISPLAYS AND PRINTERS <br> Quarterly progress report no. 1 for 7 Jan. - 6 Apr. 63 by H. Fleisher and w. Kulcke. 11 June 63, 37 p. incl. illus. tables, 5 refs. \{Contract DA-36-039-AMC-00118(E) ). Report Unclassified | Development Lab., International Business Machines, Poughkeepsie, N. Y. USE OF OPTICAL MASERS IN DISPLAYS AND PRINTERS <br> Quarterly progress report no. 1 for 7 Jan . - 6 Apr. 63 by H. Fleisher and W. Kulcke, 11 June 63, 37 p. incl. illus. tables, 5 refs. <br> (Contract DA-36-039-AMC-00118(E)). Report Unclassified |
| DESCRIPTORS: (Lasers, Focusing, Conical Refraction, Digital Deflection, Display Systems, Optical Images, Input-Outpat Devices.) | DESCRIPTORS: (Lasers, Focusing, Conical Refraction, Digital <br> Deflection, Display Systems, Optical Images, Input-Output Devices.) |
| The objective of this investigation is a significant improvement in the state of the art among electro-optic input-output devices using the Laser as an electro-optic tool. We investigated deflection of laser beams using digital light deflectors and conical refraction, and the focusing of the beams with a Fresnel zone lens. Results indicate that laser beams can be accurately defected using digital light deflector. Conical refraction shows promise for analog deflection of beams, and the Fresnel zone lens is suitable for focusing. Conclusion indicates that digital electro-optic deflection of beams is feasible and could lead to practical laser display and printing apparatus. | The objective of this investigation is a significant improvement in the state of the art among electro-optic input-output devices using the Laser as an electro-optic tool. We investigated deflection of laser beams using digital light deflectors and conical refraction, and the focusing of the beams with a Fresnel zone lens. Results indicate that laser beams can be accurately deflected using digital light deflector. Conical refraction shows promisefor analog deflection of beams, and the Fresnel zone lens is suitable for focusing. Conclusion indicates that digital electro-optic deflection of beams is feasible and could lead to practical laser display and printing apparatus. |
| AD UNCLASSIFIED | AD UNCLASSIFIED |
| Development Lab., International Business Machines, Poughkeepsie, N. Y. USE OF OPTICAL MASERS IN DISPLAYS AND PRINTERS <br> Quarterly progress report no. 1 foj an. - 6 Apr. 63 by H. Fleisher and w. Kulcke, 11 June 63, 37 p. incl. illus. tables, 5 refs. <br> (Contract DA-36-039-AMC-00118(E)). <br> Report Unclassified | Development Lab., International Busines: Machines, Poughkeepsie, N. Y. USE OF OPTICAL MASERS IN DISPLAYS AND PRINTERS <br> Quarterly progress report no. 1 for 7 Jan. - 6 Apr. 63 by H. Fleisher and w. Kulcke, 11 June 63, 37 p. incl. illus. tables, 5 refs. (Contract DA-36-039-AMC-00118(E)). <br> Report Unclassified |
| DESCRIPTORS: (Lasers, Focusing, Conical Refraction, Digital Deflection, Display Systems, Optical Images, Input-Output Devices.) | DESCRIPTORS: (Lasers, Focusing, Conical Refraction, Digital Deflection, Display Systems, Optical Images, Input-Output Devices.) |
| The objective of this investigation is a significant improvement in the state of the art among electro-optic input-output devices using the Laser as an electro-optic tool. We investigated deflection of laser beams using digital light deflectors and conical refraction, and the focusing $\therefore$ the bearns with a Fresnel zone lens. Results indicate that laser beams can he accurately defected using digital light deflector. Conical refraction shows promise for analog deflection of beams, and the Fresnel zone lens is suitable for focusing. Conclusion indicates that digital eiectro-optic deflection of beams is feasible and could lead to practical laser display and printing apparatus. | The objective of thisinvestigation is a significant improvement in the state of tie: : among electro-optic input-output devices using the Laser as an electr. sptic tool. We investigated deflection of laser beams using digital light u inectors and conical refraction, and the focusing of the beams with a Fresnel zone lens. Results indicate that laser baams can be accurately defected using digital light deflector. Conical refraction shows f:omis: for analog deflection of teams, and the Fresnel zone lens is suitade for focusing. Conclusion indicates that digital electro-optic deflection of ieam:is feasible and could lead to practical laser display and printing apparatus. |


[^0]:    2 Szivessy, G: Kristalloptik, In Geiger and Scheel's Handbuch d. Physik, Vol. 20, pp. 635-904 Berlin, Springer 1928

